

Nanofabrication with RAITH EBL and FIB equipment

Satellite Workshop - ImagineNano 2015 Conference, Bilbao / Spain

Bilbao Exhibition Centre

Tuesday, 10th March 2015 from 15:00 to 18:30

Agenda:

First Session : Nanofabrication with electrons

- 15:00 **Welcome**
Vincent Morin, Raith GmbH, Dortmund, D
- 15:05 **News on Products & recent Application highlights**
Andreas Remscheid, Raith GmbH, Dortmund, D
- 15:40 **Electron beam lithography: spintronics and nano-optics applications**
Luis E. Hueso, CIC NanoGUNE, Donostia-San Sebastian, E
- 16:10 **Raith EBL Applications & Nanofabrication Methods**
Mike Butler, Raith B.V., Best, NL
- 16:40 **Electron Beam Lithography – Applications at Fraunhofer HHI**
Ralf Steingrueber, Fraunhofer Heindrich Hertz Institute, Berlin, D
- 17:10 **Coffee Break**

Second Session : Nanofabrication with ions

- 17:30 **Ion column and Source Technology employing Gallium and New Ion Species for Advanced FIB Nanofabrication**
Vincent Morin, Raith GmbH, Dortmund, D
- 18:00 **High precision nanofabrication for light management at nanoscale**
Saulius Juodkasis, Centre for Micro-Photonics, Swinburne University of Technology, AU
- 18:30 **Wrap Up, Final Words, Questions & Remarks**